

Cheiron School 2012

X-ray Free Electron Laser Part-2: Beamline Part

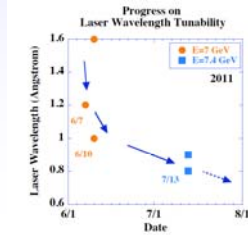
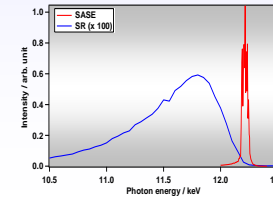
Makina YABASHI

RIKEN SPring-8 Center (RSC), Beamline R&D Group

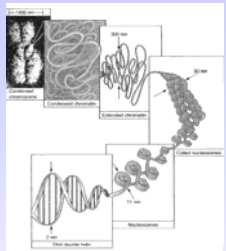
yabashi@spring8.or.jp

Sep 28, 2012 @SPring-8

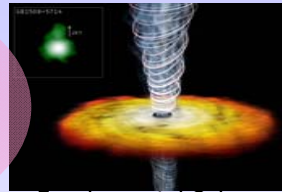
First Lasing of SACLA: June 7, 2011



XFEL explores new worlds of science



Brilliance
($\times 10^9$)

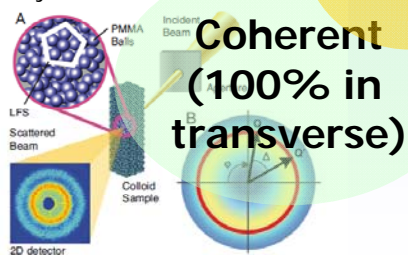


Fundamental Science:
Create Extreme State

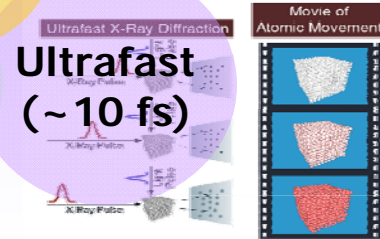
Biology & Medicine: Investigate non-crystalline materials

XFEL

Environmental & Energy Science:
Probe ultrafast reactions



Ultrafast
(~10 fs)

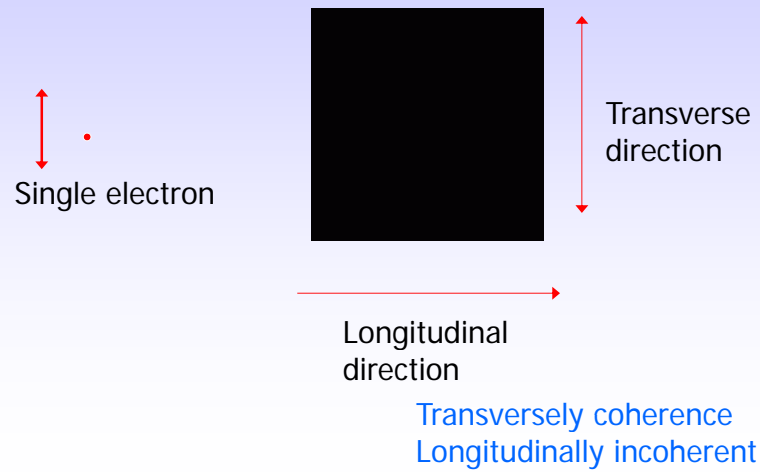


"Coherence"

- Coherent Diffraction Imaging
- Transverse coherence
- Longitudinal coherence
- Coherent radiation
- Coherent light source
- Incoherent scattering ...

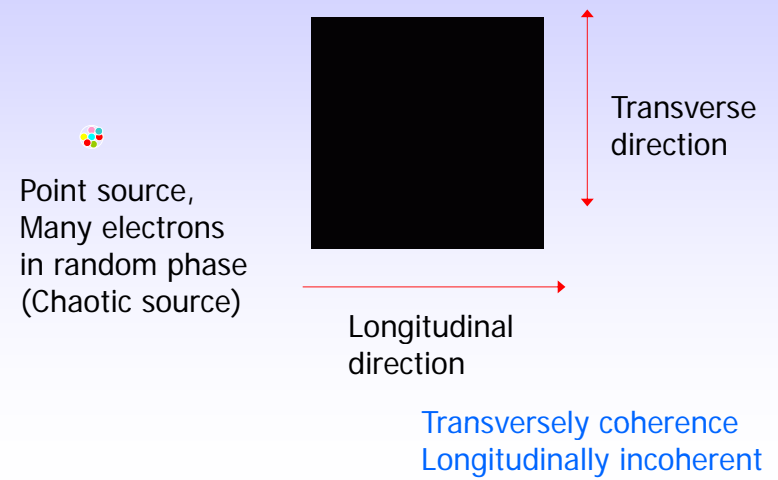
Q. Do you have physical images of coherence ?

Radiation from single electron



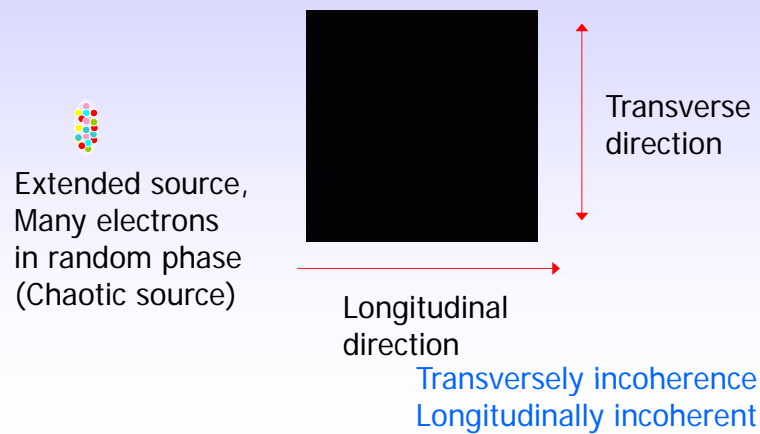
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Radiation from "point" source with many electrons



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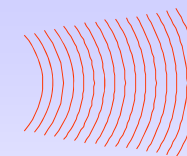
Radiation from "extended" source with many electrons



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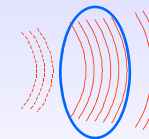
Summary

Coherent source



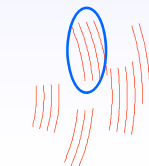
"seeded"-FEL
all electrons in phase

Point source
Multiple electrons



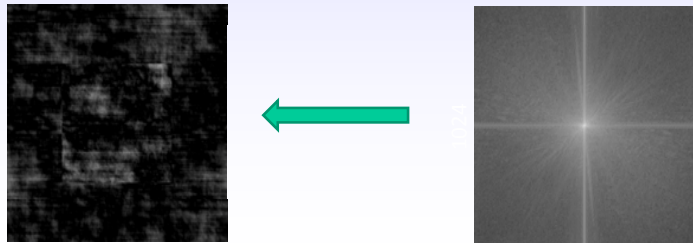
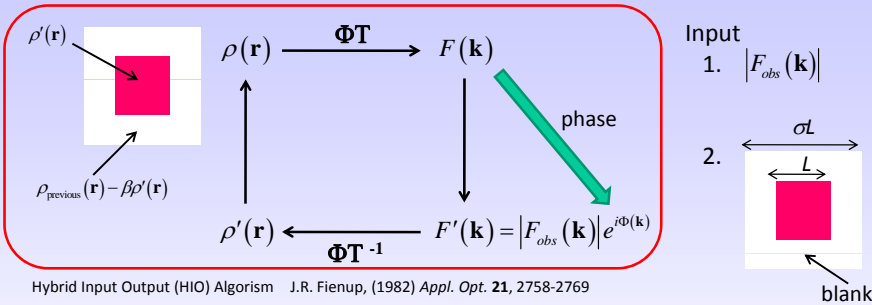
"SASE"-FEL
only neighboring
electrons in phase

Extended source
Multiple electrons



Phase retrieval with HIO (Hybrid-Input-Output) method at oversampling condition

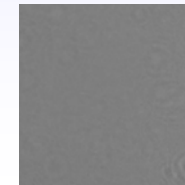
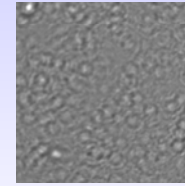
Courtesy of Joti-san



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Coherent light: dangerous probe for imperfect optics

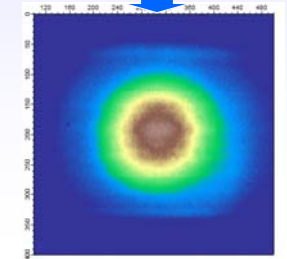
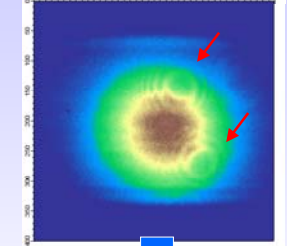
Transmission image from mid-quality beryllium foil with voids



Reflection image from mid-quality mirror



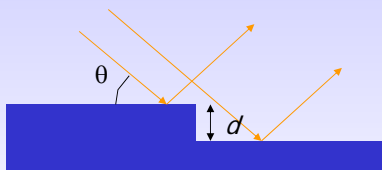
Reflection image of SACLA XFEL from double mirrors with small particles



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Mirror requirement

Ultraprecise surface figure is required to prevent unwanted speckles under coherence illumination



1st experiment of Osaka-SP8 collaboration (Mori et al, SPIE 2001)
Plane mirror is illuminated with coherent x-rays @ 1-km BL of SP8

Path difference: $\delta = 2d \sin \theta$

$\delta < \lambda/20$, $\lambda = 0.1 \text{ nm}$, $\theta = 2.5 \text{ mrad}$

$$d < \frac{\lambda}{40 \sin \theta} = \frac{0.1 \text{ nm}}{40 \times 2.5 \times 10^{-3}} = 1 \text{ nm}$$

Pre-machined



EEM



EEM+CVM



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High peak intensity

"Pulse energy": J/pls

"Peak power": W

"Photon flux": photons/pls

Ex)

Photon flux: 10^{11} photons @ $h\nu = 10 \text{ keV}$, $\tau = 10 \text{ fs}$

Pulse energy: $I = 1.6 \times 10^{-19} \text{ (J/eV)} \times 10^{11} \times 10000 \text{ (eV)}$
 $= 1.6 \times 10^{-4} \text{ (J)} = 160 \text{ uJ}$

Peak power: $P = 160 \text{ uJ} / 10 \text{ fs} = 16 \text{ GW}$

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XFEL pulse can melt or ablate materials

Absorbed energy > melting (ablation) threshold

P-beam Intensity: I (# of photon per unit area)

Absorbed photon per cell: $\mu I a^2 t$

Number of atoms in cell: $\rho N_A a^2 t / M$

Absorbed photon number per atom

$$\frac{\mu I M}{\rho N_A}$$

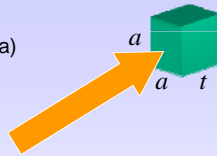
μ : linear absorption coeff.

ρ : density

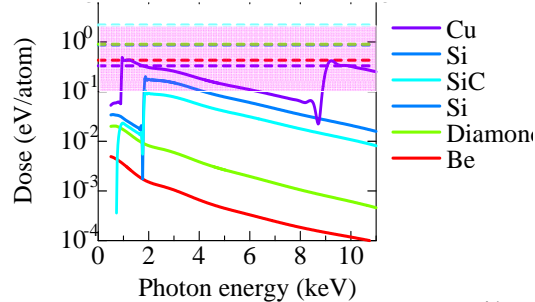
M : average atomic weight

N_A : Avogadro number

→ Dose (eV/atom)



Calculation for unfocused XFEL beam @SACLA



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How to use XFEL ?

High peak power/flux in very short pulses

Can easily destroy samples after irradiation

Shot-to-shot change of pulse characters



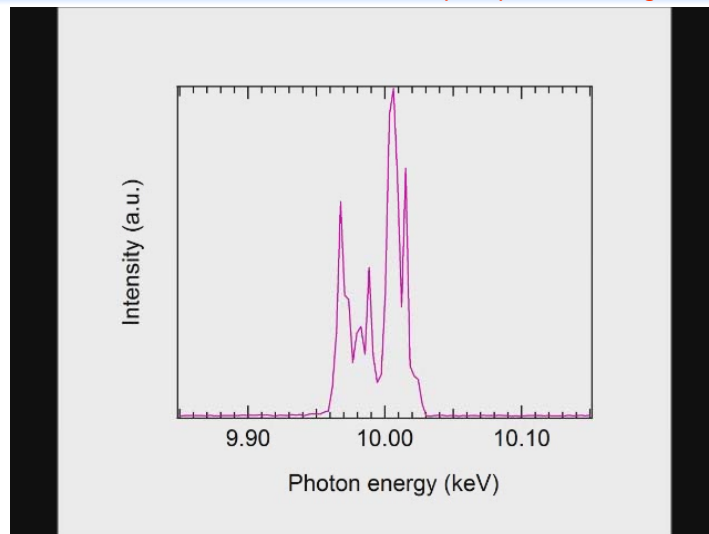
Single-shot measurement

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SACLA Single-shot spectra

Central energy is stable

Spike profiles change in every shot



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Example of XFEL Beamline: SACLA

